

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Priority** Application Serial No. ....09/449,025  
**Priority** Filing Date ..... November 24, 1999  
Inventor ..... Shozo Nagano et al.  
Assignee ..... Honeywell International, Inc.  
**Priority** Group Art Unit ..... 1775  
Examiner ..... Unknown  
Attorney's Docket No. .... 30-5000-(4015)-Div3  
Title: Physical Vapor Deposition Target

**PRELIMINARY AMENDMENT**

To: Box Patent Application  
Assistant Commissioner for Patents  
Washington, D.C. 20231

From: Mark S. Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
Wells, St. John, Roberts, Gregory & Matkin P.S.  
601 West First Avenue, Suite 1300  
Spokane, WA 99201-3817

Sir:

Please enter the following amendments prior to examining the above-identified application.

**AMENDMENTS**

**In the Title**

Please replace the title with the following: --PHYSICAL VAPOR  
DEPOSITION TARGET.--

**In The Specification**

At page 1 before the "Technical Field" section, please insert the following:

**--RELATED PATENT DATA**

This patent resulted from a divisional application of U.S. Patent  
Application Serial No. 09/449,025, filed November 24, 1999, entitled "Physical

EL465854344US

Patented 09/24/2001

Vapor Deposition Targets, Conductive Integrated Circuit Metal Alloy Interconnects, Electroplating Anodes, and Metal Alloys For Use as a Conductive Interconnection in an Integrated Circuit", naming Shozo Nagano, Hinrich Hargarter, Jianxing Li and Jane Buehler as inventors, the disclosure of which is incorporated by reference.--

**In the Claims**

Cancel claims 1-41, 45-52, and 56-59 without prejudice.

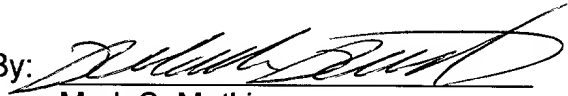
FOIA b 7 - DATED 08/20/2013

**REMARKS**

This application is a divisional application of U.S. Patent Application Serial No. 09/449,025. Original claims 1-41, 45-52, and 56-59 have been canceled without prejudice. Claims 42-44 and 53-55 remain in the application for consideration.

Respectfully submitted,

Dated: 2-13-01

By:   
Mark S. Matkin  
Reg. No. 32,268

09/449,025